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IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent of :

Shoriki NARITA et al. :

Patent No. 6,818,975 :

Issued November 16, 2004 :

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED
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SUBMISSION OF REFERENCES

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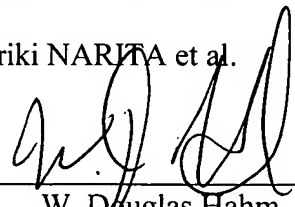
Sir:

Applicants hereby request that the copy of the attached reference JP 6-232132 be placed in the file for the above-referenced application. The reference was cited in a corresponding Japanese application on September 7, 2004.

Respectfully submitted,

Shoriki NARITA et al.

By


W. Douglas Hahm
Registration No. 44,142
Attorney for Patentees

WDH/gtg
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
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